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Pre Amdt
SDavis
4/30/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: §
Giles § Attorney Docket No.: 26114.4
Serial No.: US National Phase §
of PCT/GB00/00301 § International Filing Date:
§ 02 February 2000
Filed: Herewith §
For: ION SOURCE FOR MASS ANALYSER § Priority Date Claimed:
§ 11 February 1999

BOX APPLICATION
Attention: DO/EO/US
Commissioner For Patents
Washington, D.C. 20231

PRELIMINARY AMENDMENT

Dear Sir:

Prior to the initial examination of the above-identified application, please amend the application as follows:

IN THE CLAIMS:

2. (Amended) An ion source as claimed in claim 1, in which the interface chamber has a bend therein to introduce turbulence into the flow of gas and entrained sample ions as they flow along the said flow passage, the bend being formed between the said entrance aperture and the said exit aperture.

3. (Amended) An ion source as claimed in claim 1, in which the interface chamber has a first passage adjacent the entrance aperture, and a second passage adjacent the exit aperture, the first and second passages communicating with each other and intersecting at an angle of approximately 90° to each other such that the intersection lies between the said entrance and exit apertures.

6. (Amended) An ion source as claimed in claim 3, in which both the first passage and the second passage have a length substantially longer than their respective widths.